

Simulation Study of GEM Gating for LC TPC



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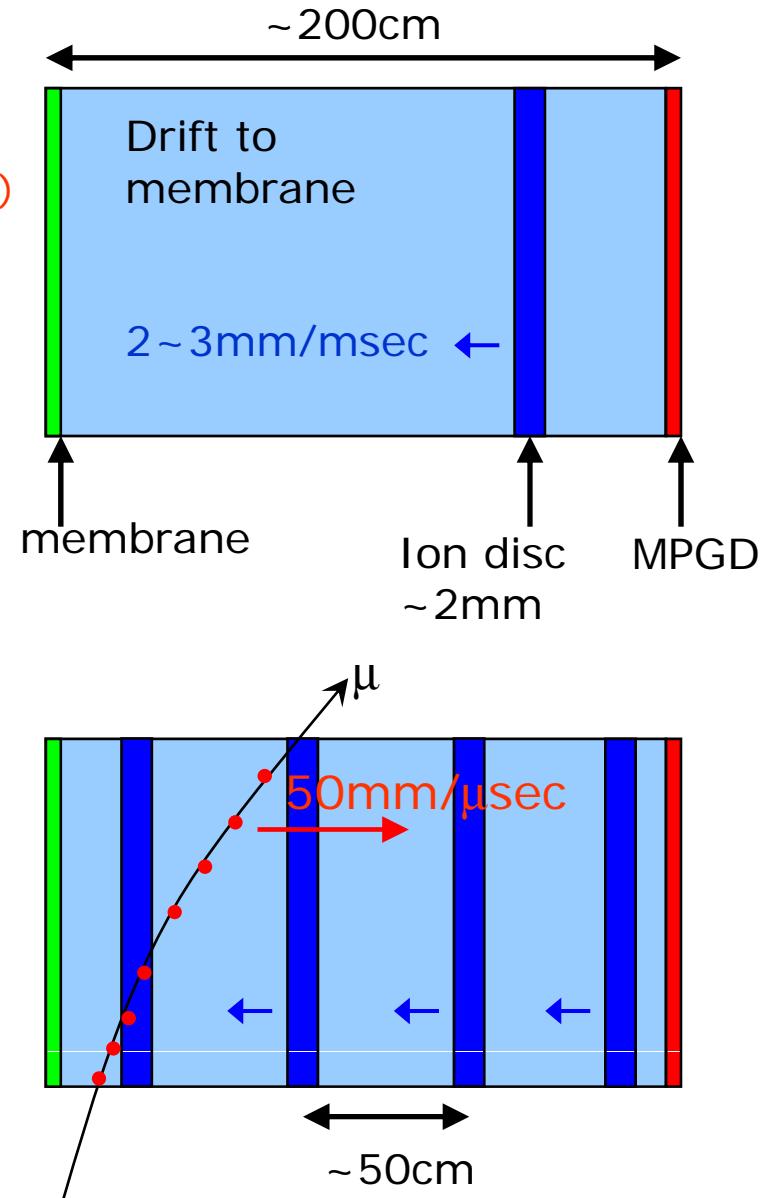
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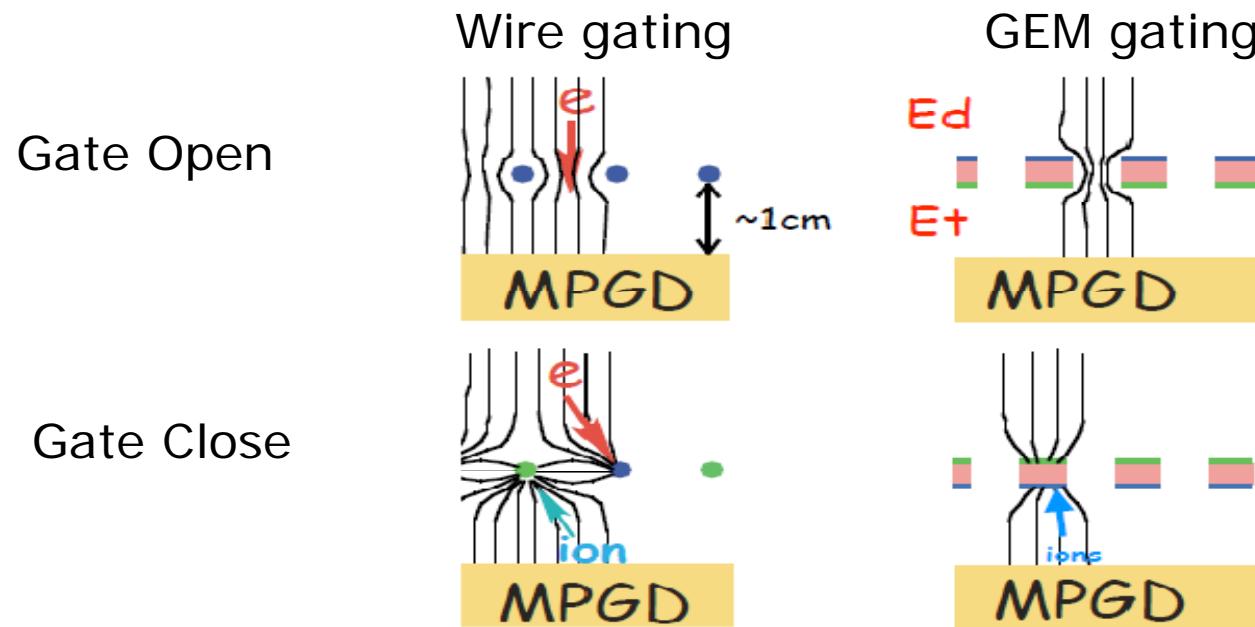
Why do we need Gate?

- Ions are generated at MPGD by gas multiplications.
 - Gain ~ several $\times 10^3$
 - Self ion suppression of MPGD $O(10^{-2}) \sim O(10^{-3})$
- One bunch train (1msec) produces 2~3mm thick ion-dense disc.
 - cf. mobility of isoC₄H₁₀ ion in Ar is $1.56 \times 10^{-3} \text{ cm}^2/\text{Vmsec}$
 - Charge density of the disc assuming 1% occupancy is $O(0.1) \sim O(1) \text{ fC/mm}^3$
- Ion discs drift only ~50cm and never reach central membrane between two trains (200msec)
- Primary electrons produced by charged tracks go through a few ion discs and the **position information is deteriorated**.
- **Ions must be shut off by gate.**
 - Ion feedback probability should be less than a few $\times 10^{-4}$



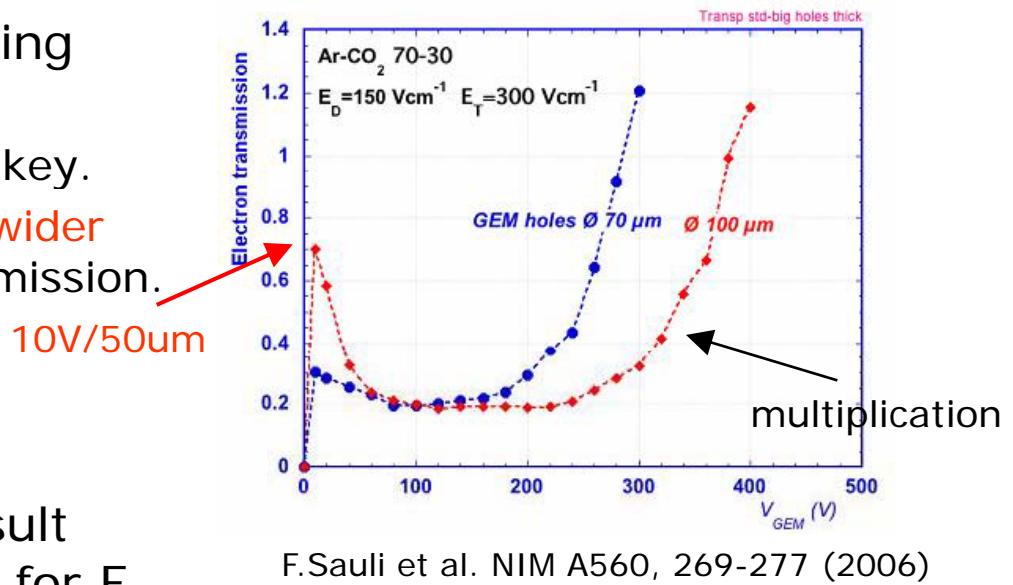
Gating Method

- Conventional Wire gating
 - Well understood
 - High electron transmission >90%
 - Large ExB effect under high B field
 - ~10% electron has deteriorated information
 - Should be designed to avoid wire vibration due to HV pulsing
 - Mechanical issue to string wires above MPGD
- GEM gating
 - Small ExB effect due to small structure
 - No vibration due to low voltage pulsing
 - Easy to mount on the multiplication GEM
 - Not well understood

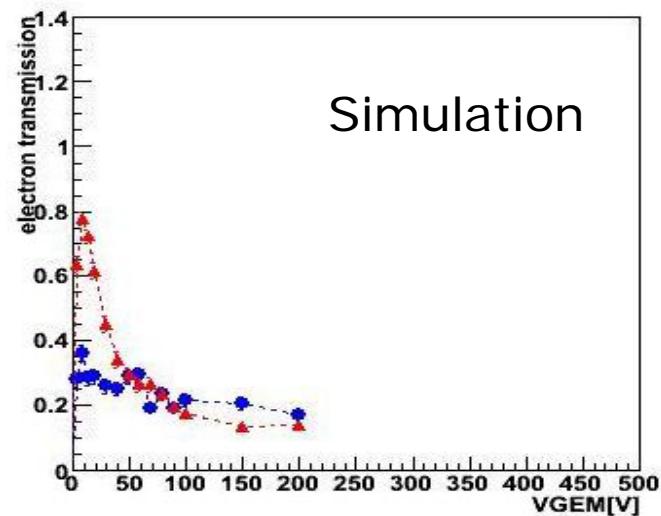


GEM Gating

- F.Sauli Proposed GEM as gating device.
 - Electron transmission is the key.
 - Low voltage operation with wider GEM holes gives good transmission.
 - 70% transmission with $Ar-CO_2=70:30$ under $B=0T$
- We can reproduce Sauli's result with Maxwell3D and Garfield for E-field calculation and electron/ion drift simulation.
- We try to optimize the GEM gating for LC TPC.
 - $Ar-CF_4\text{-isoC}_4H_{10}$
 - $B=3T$



F.Sauli et al. NIM A560, 269-277 (2006)



How to Understand the Electron Transmission

- Transmission is factorized in two part

- Transmission = Collection eff. x Extraction eff.

$$\text{Collection eff.} = \frac{\text{\#electrons arrived at Hole entrance}}{\text{\# produced electron}}$$

$$\text{Extraction eff.} = \frac{\text{\#electrons coming out from GEM hole}}{\text{\#electrons arrived at Hole entrance}}$$

- Parameters to be optimized.

- E field

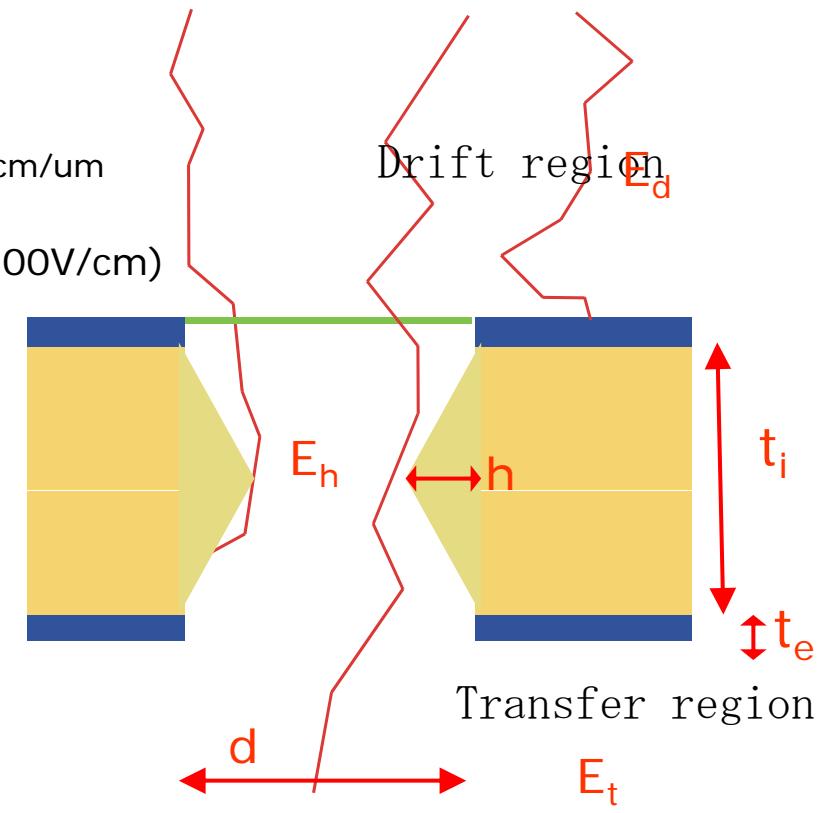
- E_d : E field at drift region
 - Restricted to have the drift velocity > 5cm/um
- E_h : E field at hole center (as x axis)
- E_t : E field at transfer region (fixed to 300V/cm)
 - not sensitive to transmission in B field

- GEM structure

- p : hole pitch (fixed to 140um)
- d : Hole diameter (fixed to 100um)
- h : Hole shape
 - $h=0$: cylindrical
 - $h>0$: biconical
- T_i : Insulator thickness
- T_e : Electrode thickness

- Gas

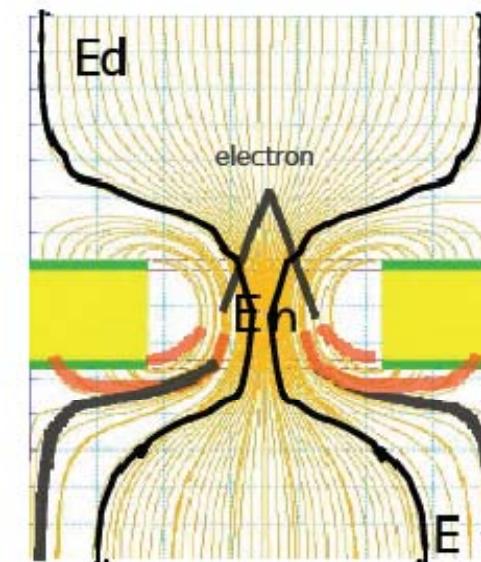
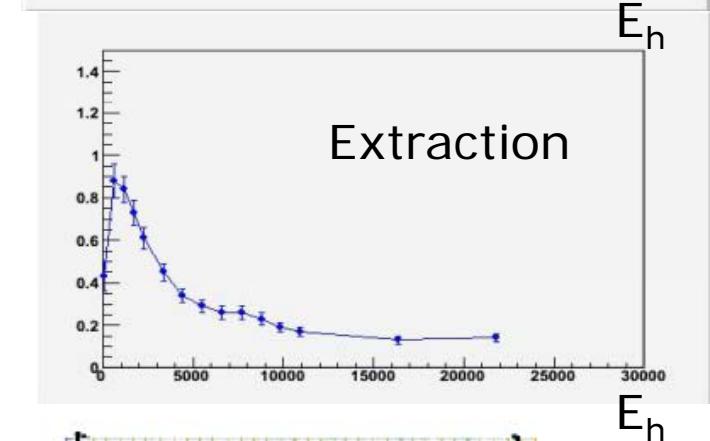
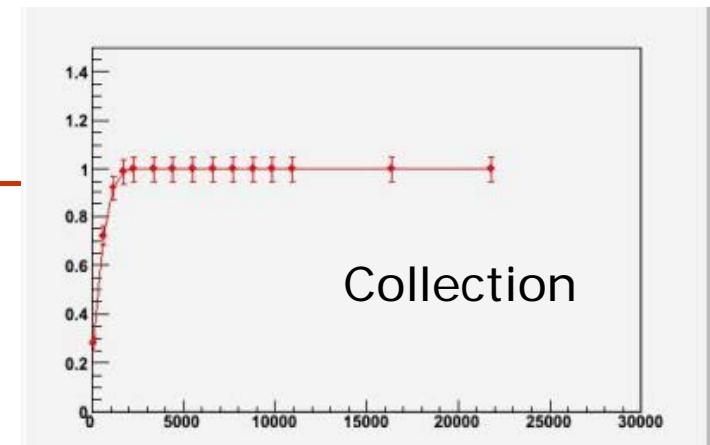
- Concentration of Ar, CF₄, isoC₄H₁₀



Collection and Extraction

- Collection efficiency is known to be a function of E_d/E_h .
 - Collection efficiency is 100% when $E_d/E_h < 0.03$ for 70um hole diameter.
 - This is relaxed when hole becomes larger.
 - Slightly worse in B field due to Lorentz angle than no B field.

- Extraction efficiency in B field is more complicated.
 - Entering position can be close to wall due to Lorentz angle
 - Area of penetrating field line becomes small as E_h increases.
 - Electron can spread due to diffusion
 - Absorption by wall
 - Follow field lines returning to GEM electrode

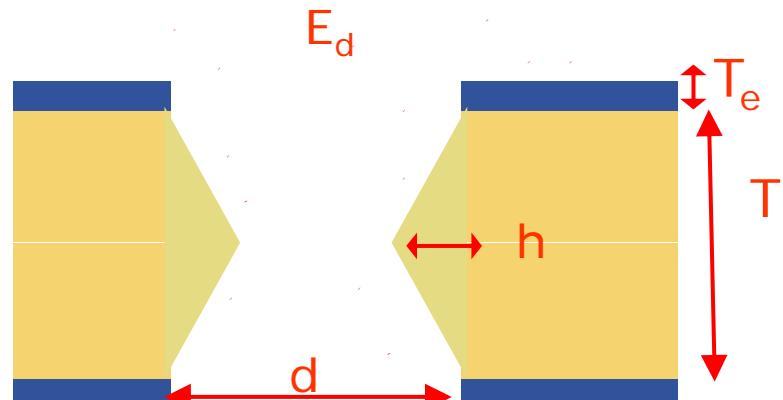


Transmission largely depends on gas.

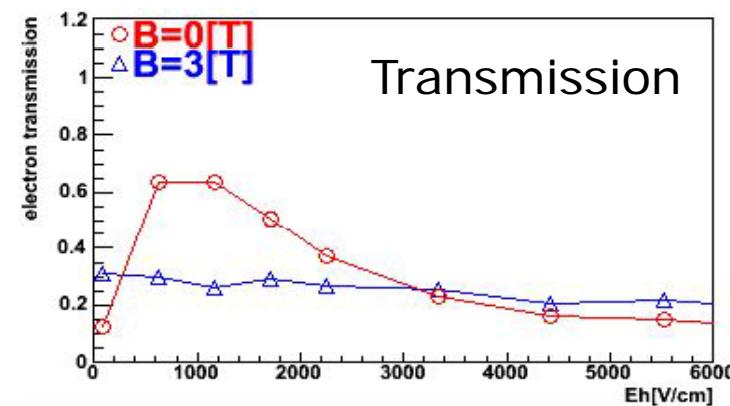
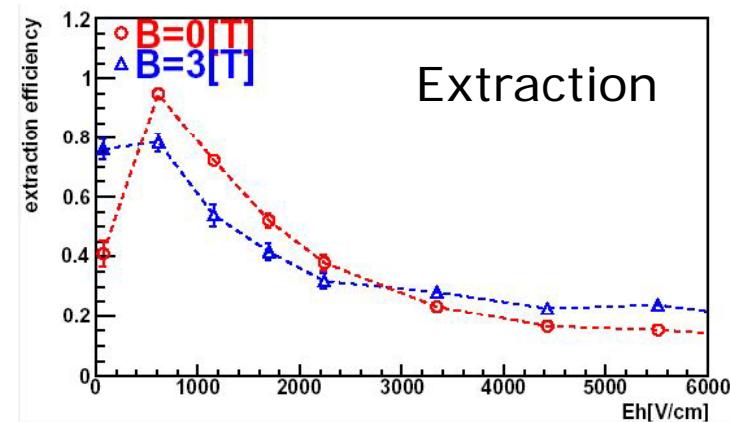
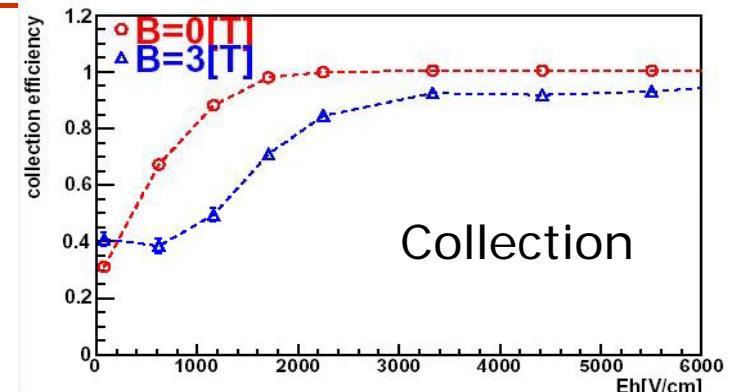
Setup

- Same setup as Sauli's except hole shape, gas and B field.

- Electron transmission is ~30% in $B=3\text{T}$
 $E_D=150 \text{ [V/cm]}$
 $E_T=300 \text{ [V/cm]}$ (fixed)
Hole pitch $p=140[\mu\text{m}]$ (fixed)
hole diameter $d=100[\mu\text{m}]$ (fixed)
Insulator thickness $T_i=50[\mu\text{m}]$
Electrode thickness $T_e=5[\mu\text{m}]$
Hole shape $h=0[\mu\text{m}]$, cylindrical
GAS Ar-CF₄-isoC₄H₁₀(96:3:1)
 $B= 3[\text{T}]$



- Start from this setup



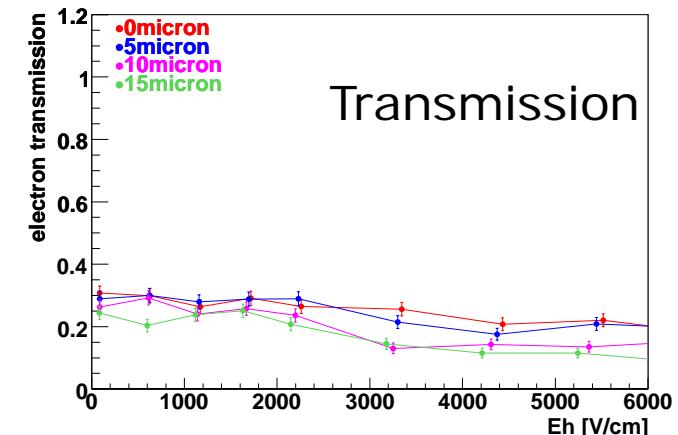
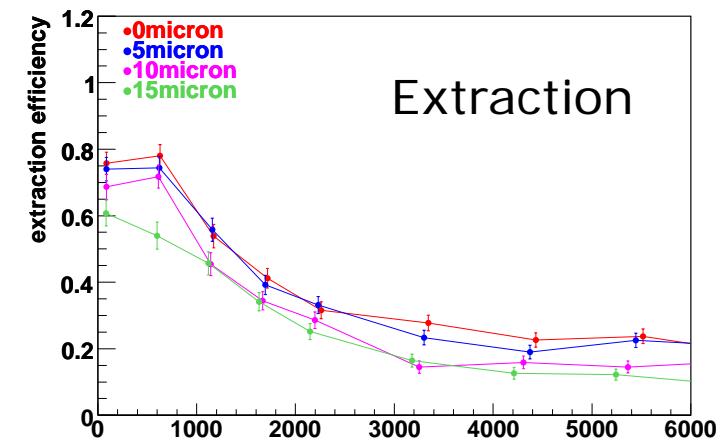
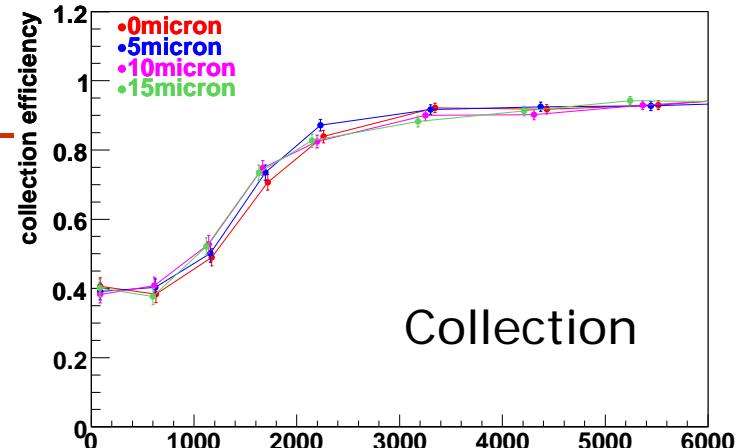
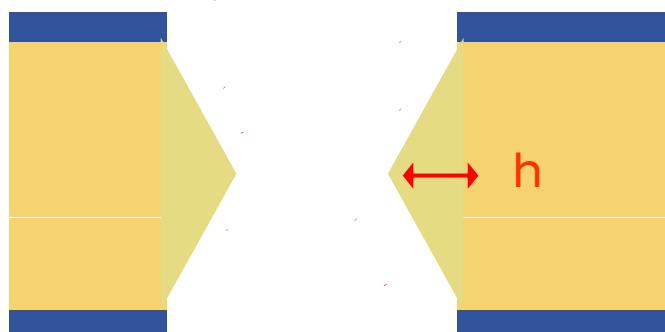
Hole shape

$h=0, 5, 10, 15 \text{ [um]}$

- Under non-B field, hole shape does not affect the transmission.
 - Electron follows field lines
- But under 3T B field, extraction efficiency is worse as h increases
 - entering position of electron can be close to GEM wall due to Lorentz angle
 - Electrons can not follow the field line due to Lorentz angle and are absorbed

Best parameter

$h=0 \text{ [um]}$



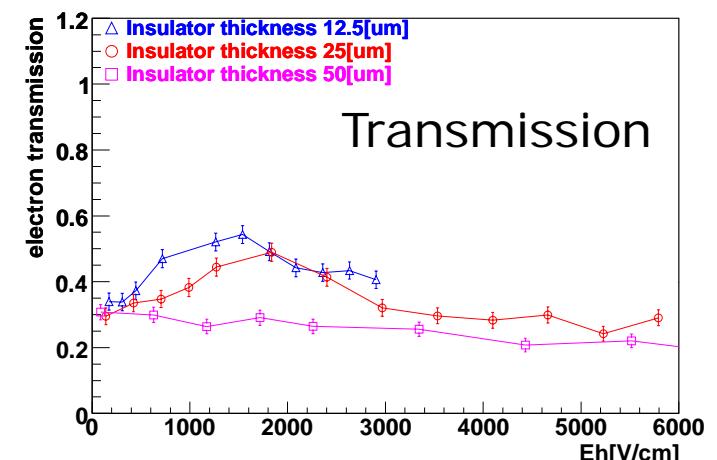
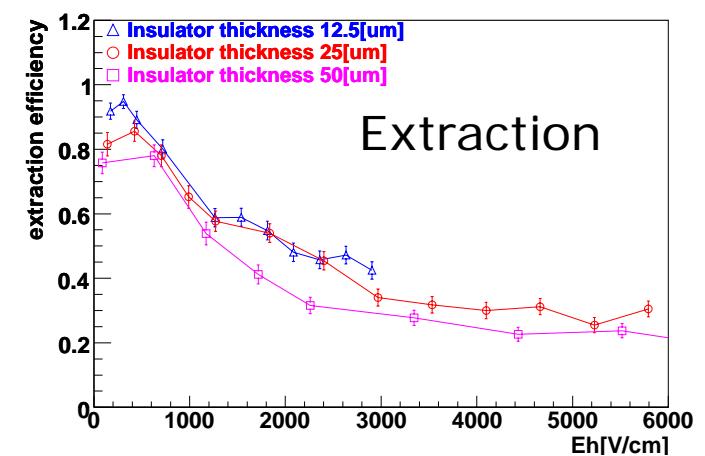
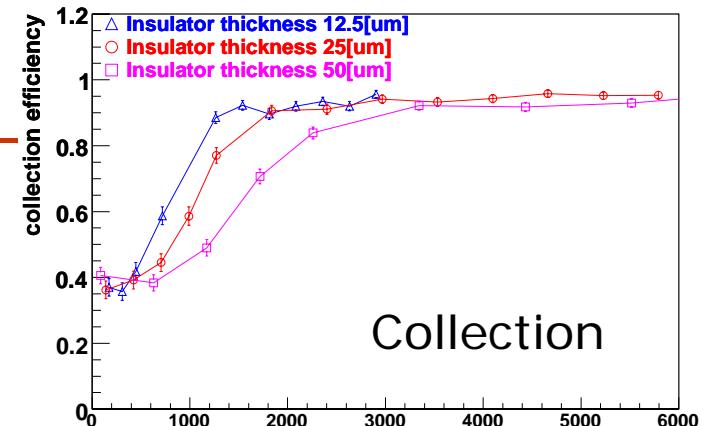
Insulator Thickness

$T_i = 12.5, 25, 50 \text{ [um]}$

- Both collection and extraction becomes better as T_i decreases
 - E field at edge of hole becomes larger
→ field line can be easy to penetrate center of hole
 - E_h becomes lower
 - Small diffusion → better extraction

Best parameter

$T_i = 12.5 \text{ [um]}$

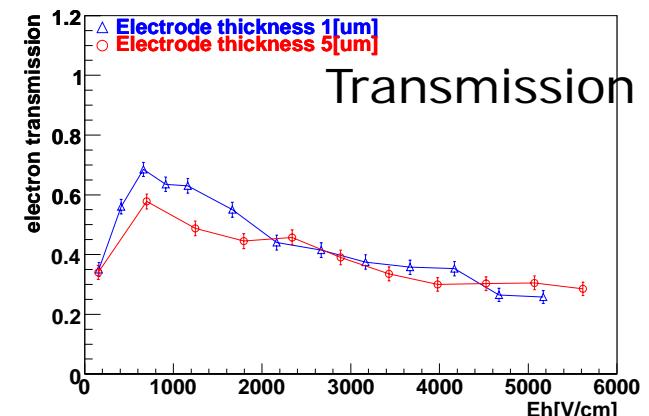
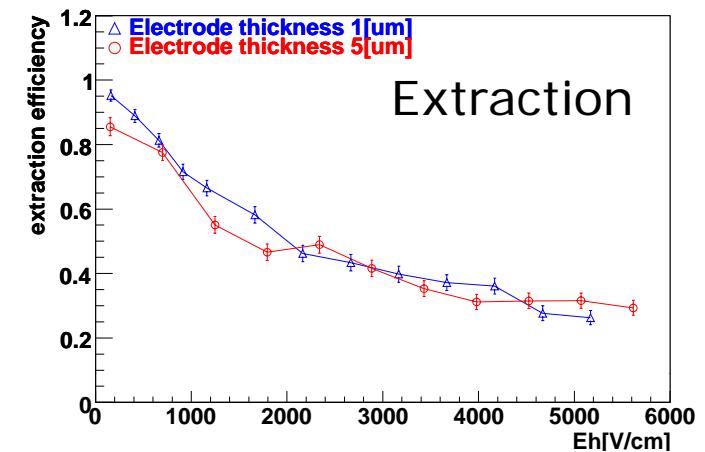
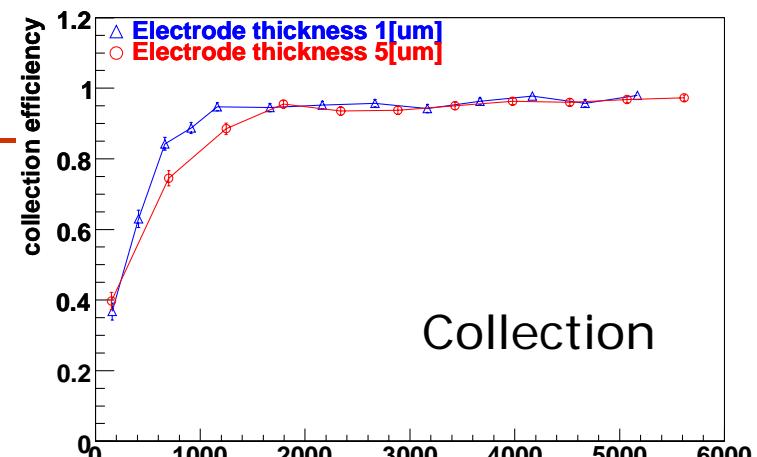


Electrode Thickness

$T_e = 1, 5 \text{ [um]}$

- Both collection and extraction becomes better as T_e decreases
 - Same reason as insulator thickness

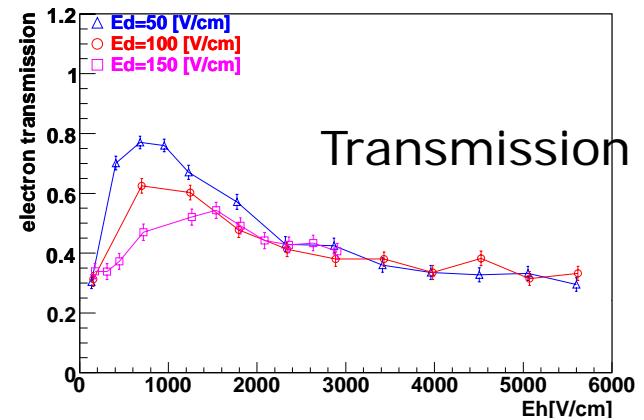
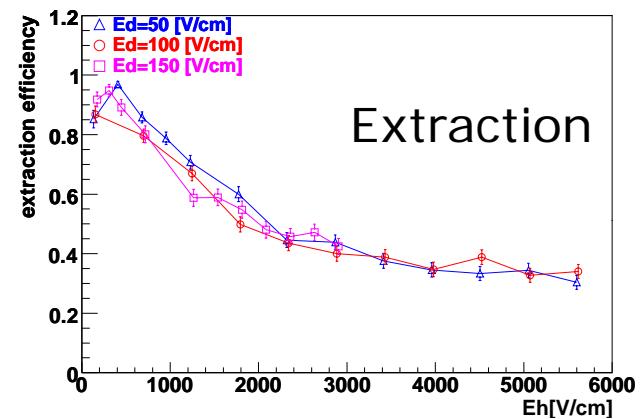
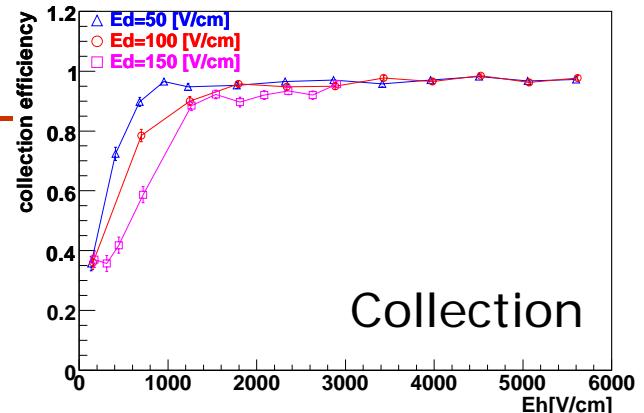
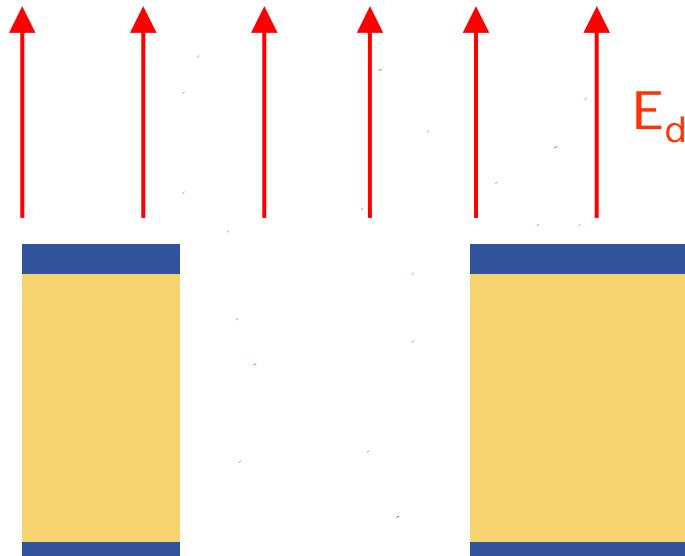
Best parameter
 $T_e = 1 \text{ [um]}$



Ed dependence

$E_d = 50, 100, 150$ [V/cm]

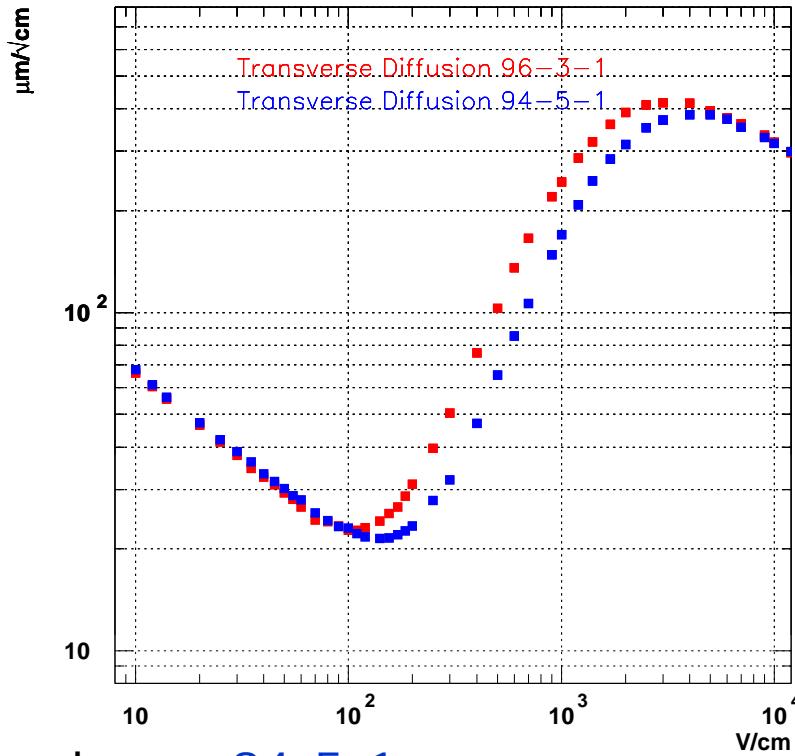
- Collection becomes better as E_d decreases.
 - E_d/E_h dependence
- $E_d=50$ [V/cm] gives best transmission but drift velocity is smaller than our requirement, 5 [cm/um].
- So we choose $E_d = 100$ [V/cm]



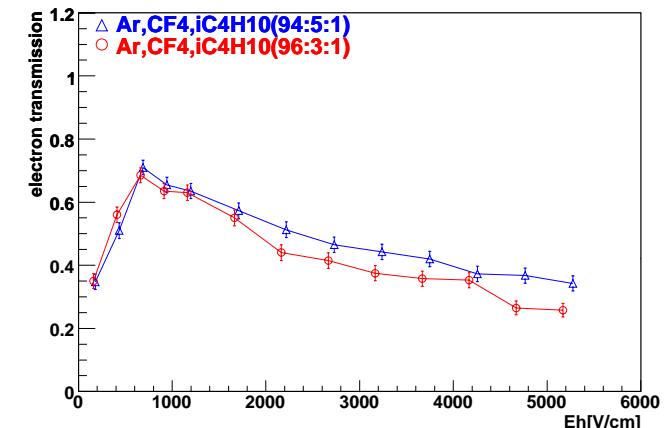
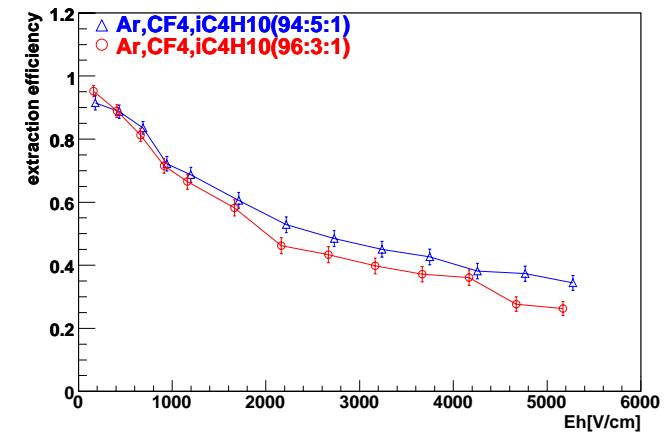
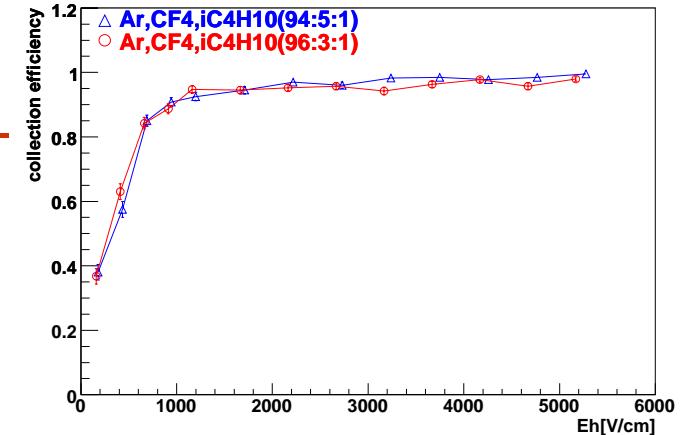
Gas Concentration

Ar-CF₄-isoC₄H₁₀= 94:5:1, 96:3:1

- For 94:5:1, we increase Ed to 120 [V/cm] to meet the requirement, drift velocity > 5 [cm/um]
- 94:5:1 gives better extraction due to small diffusion around 1000 [V/cm]

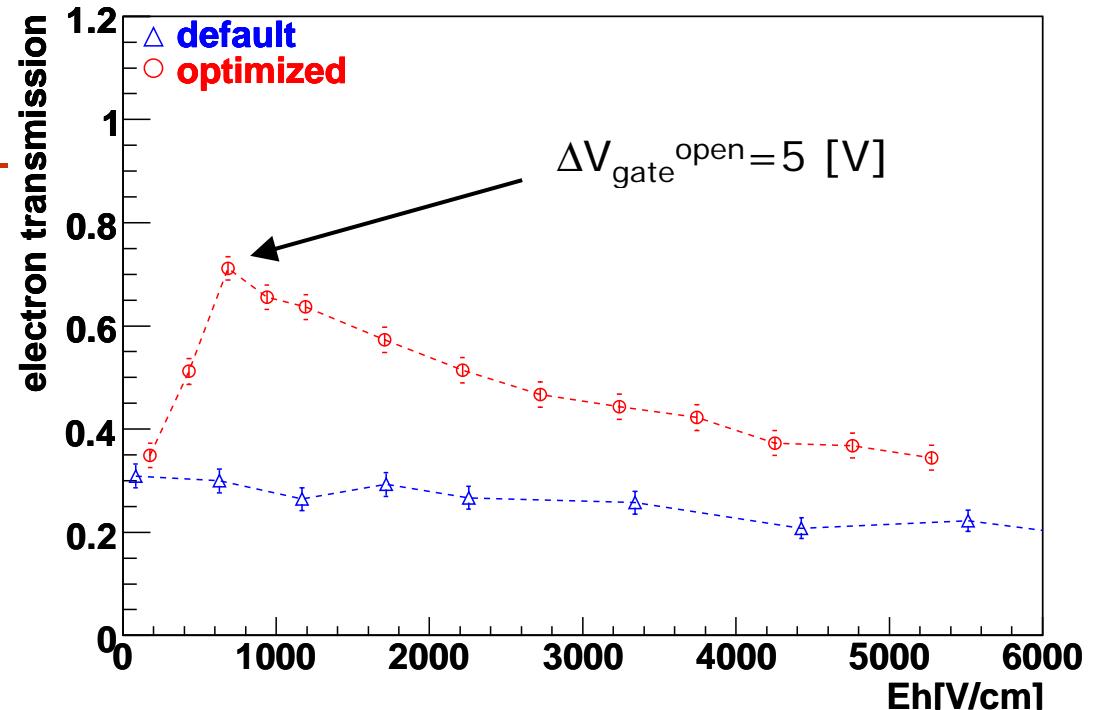


- we choose 94:5:1.



Optimized Setup

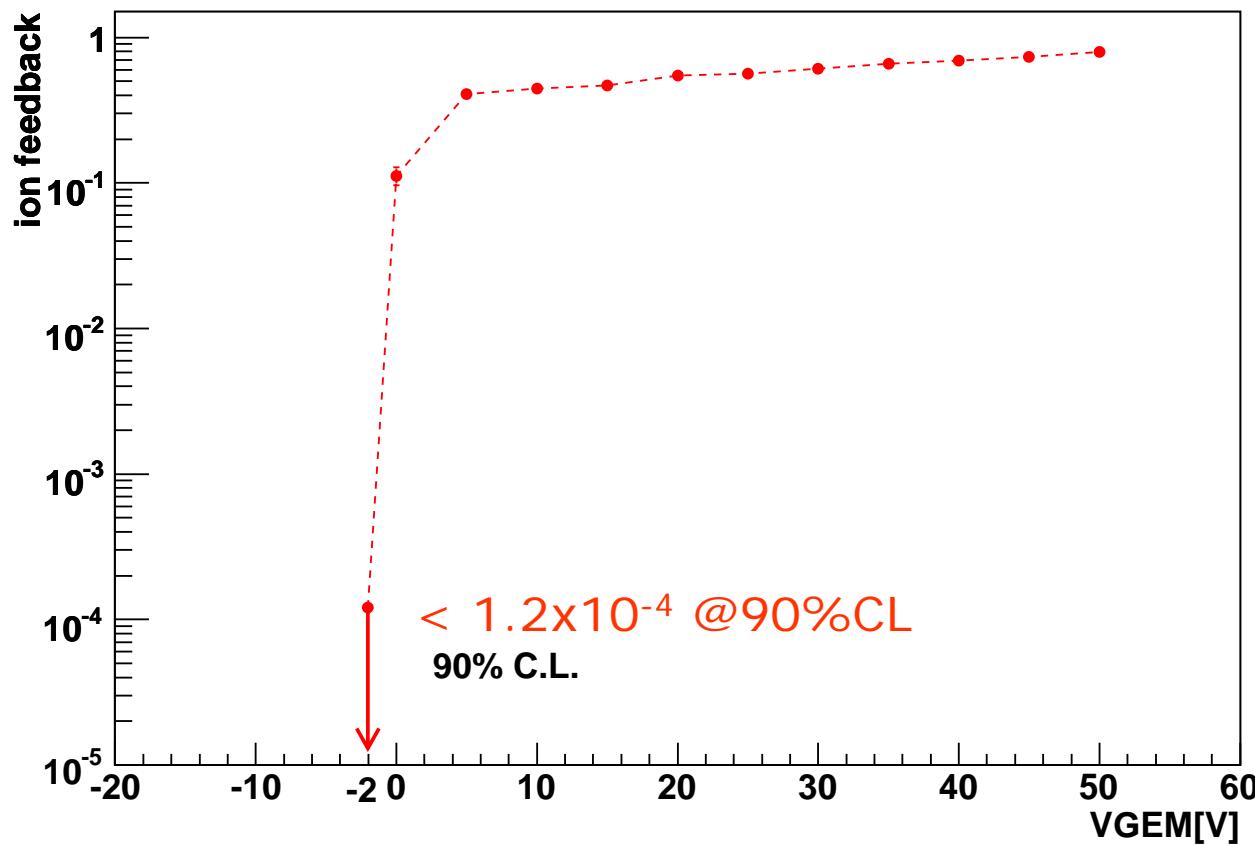
- 135% improvement from **default** setup
- 71% efficiency are achieved with optimized GEM and $\Delta V_{\text{gate}}^{\text{open}}=5 \text{ [V]}$



	default	optimized	improvement
Hole shape	Cylindrical	Cylindrical	0%
Insulator Thickness	50[um]	12.5[um]	55%
Electrode Thickness	5[um]	1[um]	15%
E_d	150[V/cm]	120[V/cm]	25%
Gas	Ar-CF ₄ -isoC ₄ H ₁₀ 96:3:1	Ar-CF ₄ -isoC ₄ H ₁₀ 94:5:1	5%
Transmission	30%	71%	135%

Ion Transmission

- $\Delta V_{\text{gate}}^{\text{close}} = -2V$ is enough for ion transmission of less than a few $\times 10^{-4}$
 - We simulate 20k ion events with the optimized setup for electron transmission but no ions pass the GEM gate.
 - 90% C.L. upper limit on ion transmission by Gate is 1.2×10^{-4}
 - If ion suppression by multiplication GEM is included, ion transmission is less than a few $\times 10^{-6}$ for double GEM.



Towards Measurement

- We are preparing to measure the electron transmission with 25um thick and $\phi=90\text{um}$ GEM
 - OT at Saga : Ar- $\text{isoC}_4\text{H}_{10}$
 - 1T at KEK : Ar- CF_4 - $\text{isoC}_4\text{H}_{10}$
- Discussion to Scienergy on the production of optimized GEM
 - Plan to purchase 12.5um thick polyimide
 - Wet etching may be better to make larger hole.

Summary

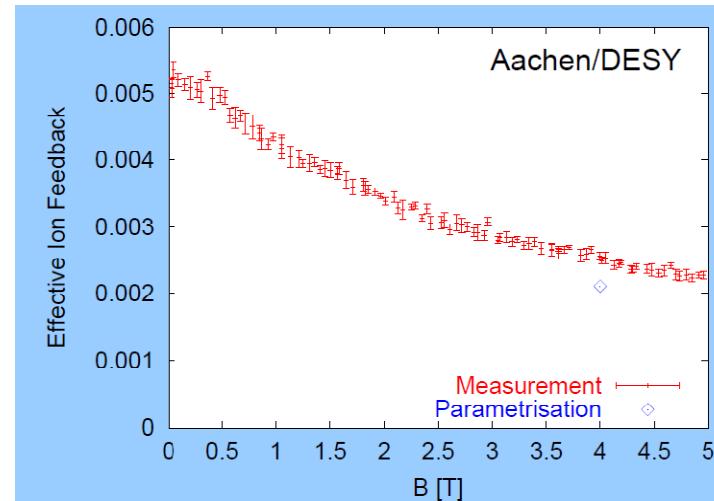
- We studied simulation of GEM gating
- E fields, GEM structure and gas mixture are optimized
 - Lower E_d , thinner GEM and lower diffusion gas
 - Electron transmission 71%
 - → about 15% degradation on position and dE/dx resolutions
 - Ion transmission less than 1.2×10^{-4}
 - < a few $\times 10^{-6}$ including self ion suppression capability
- Low voltage operation is enough for gating
 - $\Delta V_{\text{gate}}^{\text{open}} = 5 \text{ [V]}$
 - $\Delta V_{\text{gate}}^{\text{close}} = -2 \text{ [V]}$
- We are preparing to measure the electron transmission under 1T
 - Need to measure it under 3~4T, of course.



Backup

Self-Suppression Capability of Ion feed back

- MicroMEGAS
 - A few $\times 10^{-3}$
- GEM
 - Triple GEM optimized case : a few $\times 10^{-3}$
 - Double GEM non-optimized case : a few $\times 10^{-2}$



LCWS 04 Paris, M.Weber